

IN THE CLAIMS:

Please CANCEL claim 37 without prejudice or disclaimer in accordance with the following:

1. (PREVIOUSLY PRESENTED) A heating crucible for a deposition apparatus, comprising:
 - a main body having a space which receives an organic compound and a nozzle through which the organic compound, vaporized, is discharged, the nozzle being defined in an upper wall of the main body;
 - fixing portions suspended from an inner wall of the main body;
 - an inner member supported at positions along an outer circumference thereof by the fixing portions to face the nozzle, the inner member having one or more separate openings formed therein along the outer circumference thereof and between the supporting positions of the fixing portions, borders of the openings being defined by separate notches in the outer circumference and the inner wall of the main body, so as to allow for a transmittance of the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through each of the openings.
2. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein:
 - the inner member further comprises a baffle board formed on the area that faces the nozzle, and
 - the one or more openings are formed around an edge of the baffle board.
- 3-5. (CANCELED)
6. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein the one or more openings are formed at regular intervals around the edge of the inner member.
7. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein a sum of areas of the one or more openings of the inner member is equal to or greater than an area of the nozzle.

8. (ORIGINAL) The heating crucible of claim 1, wherein a distance between the nozzle and the inner member is from a radius of the nozzle to 9/10 of a distance between the nozzle and an inner bottom surface of the main body.

9. (ORIGINAL) The heating crucible of claim 1, wherein the main body comprises a cap on which the nozzle is formed and a main body part in which the space is formed.

10. (ORIGINAL) The heating crucible of claim 1, further comprising a heater which is provided to the main body and/or the nozzle.

11. (PREVIOUSLY PRESENTED) A deposition apparatus for forming a deposition film on a substrate, comprising:

a vacuum chamber which receives the substrate; and

a heating crucible which is installed opposite to the substrate and vaporizes an organic compound provided thereto, wherein the heating crucible comprises:

a main body having a space which receives an organic compound and a nozzle through which the organic compound, vaporized, is discharged, the nozzle being defined in an upper wall of the main body;

fixing portions suspended from an inner wall of the main body;

an inner member supported at positions along an outer circumference thereof by the fixing portions to face the nozzle, the inner member having one or more separate openings formed therein along the outer circumference thereof and between the supporting positions of the fixing portions, borders of the openings being defined by separate notches in the outer circumference and the inner wall of the main body, so as to allow for a transmittance of the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through each of the openings.

12. (PREVIOUSLY PRESENTED) The deposition apparatus of claim 11, wherein: the inner member further comprises a baffle board formed on the area that faces the nozzle, and the one or more openings are formed around the edge of the baffle board.

13-15. (CANCELED)

16. (PREVIOUSLY PRESENTED) The deposition apparatus of claim 11, wherein a sum of areas of the one or more openings of the inner member is equal to or greater than an area of the nozzle.

17. (ORIGINAL) The deposition apparatus of claim 11, wherein a distance between the nozzle and the inner member is from a radius of the nozzle and 9/10 of a distance between the nozzle and an inner bottom surface of the main body.

18. (ORIGINAL) The deposition apparatus of claim 11, wherein the main body comprises a cap on which the nozzle is formed and a main body part in which the space is formed.

19. (ORIGINAL) The deposition apparatus of claim 11, wherein the heating crucible further comprises a heater which is provided to the main body and/or the nozzle.

20. (CANCELED)

21. (ORIGINAL) The heating crucible of claim 1, further comprising a temperature sensing unit which senses a temperature of the organic compound.

22. (ORIGINAL) The heating crucible of claim 1, wherein:
the inner member further comprises a baffle board formed on the area that faces the nozzle, and
the baffle board is narrower than a sectional area of the space.

23. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein the one or more openings have a predetermined area so as to prevent a pressure difference between a space below the inner member and a space above the inner member.

24. (ORIGINAL) The heating crucible of claim 1 wherein the nozzle has a vertical axis that does not match with that of the opening so as to prevent the organic compound, in a predetermined form, from being transmitted through the nozzle.

25. (PREVIOUSLY PRESENTED) The heating crucible of claim 1, wherein: the inner member further comprises a baffle board formed on the area that faces the nozzle, and the baffle board blocks the organic compound, in a form of a lump, from being transmitted through the nozzle.

26. (ORIGINAL) The heating crucible of claim 1, wherein the inner member has a cross-section that is substantially the same as that of the space of the main body.

27-31. (CANCELED)

32. (PREVIOUSLY PRESENTED) A method of producing an electroluminescent (EL) device having an organic compound, the method comprising:
obtaining a substrate of the EL device;
depositing a layer of the organic compound on the substrate using a deposition apparatus having a heating crucible including a main body which receives the organic compound, a nozzle defined in an upper wall of the main body, fixing portions suspended from an inner wall of the main body, and an inner member supported at positions along an outer circumference thereof by the fixing portions to face the nozzle, the inner member having one or more separate openings formed therein along the outer circumference thereof and between the supporting positions of the fixing portions, borders of the openings being defined by separate notches in the outer circumference and the inner wall of the main body, so as to allow for a transmittance of the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through each of the openings; and
deflecting the transmitted organic compound via the upper wall of the main body.

33. (ORIGINAL) The method of claim 32, wherein the inner member prevents the organic compound, in a form of a lump, from being deposited on the substrate.

34. (CANCELED)

35. (PREVIOUSLY PRESENTED) A heating crucible for a deposition

apparatus, comprising:

- a main body having a space therein defined by a cylindrical wall and an upper wall which receives an organic compound and a nozzle through which the organic compound, vaporized, is discharged, the nozzle being defined in the upper wall of the main body;

- fixing portions suspended from an inner wall of the main body;

- a baffle board parallel with the upper wall, having one or more separate openings formed therein, that is supported by the fixing portions at positions along an outer circumference of the baffle board between the openings, borders of the openings being defined by notches in the outer edge of the baffle board and the wall of the main body, so as to allow for a transmittance of the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the one or more openings.

36. (PREVIOUSLY PRESENTED) A deposition apparatus for forming a deposition film on a substrate, comprising:

- a vacuum chamber which receives the substrate; and

- a heating crucible which is installed opposite to the substrate and vaporizes an organic compound provided thereto, wherein the heating crucible comprises:

- a main body having a space therein defined by a cylindrical wall and an upper wall which receives an organic compound and a nozzle through which the organic compound, vaporized, is discharged, the nozzle being defined in the upper wall of the main body;

- fixing portions suspended from an inner wall of the main body;

- a baffle board parallel with the upper wall, having one or more separate openings formed therein, that is supported by the fixing portions at positions along an outer circumference of the baffle board between the openings, borders of the openings being defined by notches in the outer edge of the baffle board and the wall of the main body, so as to allow for a transmittance of the vaporized organic compound therethrough, wherein the upper wall is perpendicular to a transmission direction of the organic compound when the organic compound is transmitted through the one or more openings.

37. (CANCELED)